MPI TS2000-IFE Series | 200 mm Automated Probe Systems

The Dedicated System for mmW, Load-pull, SiPH and Product Engineering

MicroPositioners and High Power Probes
- Supports up to 4 RF and 10 DC MicroPositioner
- Wide range of MicroPositioners available, including large area for mmW applications
- Dedicated Coax, Triax and Kelvin probe arms

IceFreeEnvironment™
- For probing at negative temperatures in an open environment
- Using MicroPositioners and probe cards simultaneously

Probe Platen
- Stable and rigid design
- Rectangular adjustments for RF positioners
- Integrated air-cooling for maximum thermal stability
- Unique access for maintenance and service

RF Calibration
- 2 auxiliary chucks for calibration substrates
- Built-in ceramic for accurate calibration
- 1 µm flatness for consistent contact quality

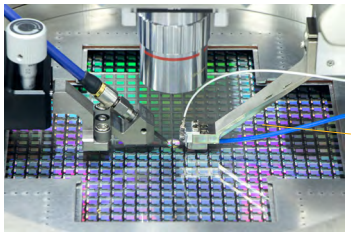
Probe Hover Control™ (PHC)
- Manual control of probes to wafer contact & separation
- Visual feedback down to 1 µm accuracy in SENTIO®

Active Vibration Isolation
- Incorporates a high performance vibration isolation platform
- Optimized total footprint
- Optional instrument shelf reduces cable lengths and increases measurement dynamic and directivity

WaferWallet® MAX Option
- Supports one 100, 150 or 200 mm SEMI standard cassette
- Four color programmable signal light tower
- Including pre-aligner and cassette scanner
- Optional top or bottom Wafer ID Reader
- Easy field upgradable

THZ-Selection Option
- Conversion into a dedicated, mmW and THz probe station
- Incorporates MPI's innovative design of frequency extender's integration which hovers over the entire 200 mm wafer
- Minimizing the distance to the DUT to a minimum, providing best possible measurement directivity and accuracy

Further Options
- Off-Axis Wafer Alignment
- Off-Axis Probe-To-Pad-Alignment
- DarkBox
- ShielDCap™



Microscope and Optics Options
- Stable microscope bridge mount with 50 x 50 x 140 mm program mable movement
- Various optics options available such as MPI iMAG® - the digital microscope or MPI AMZ12 with up to 12x optical zoom
- High Power microscopes FS70 / PSM-1000

Modular Chucks
- Various non-thermal or thermal chucks
- Choice of Triaxial or Coaxial connection
- Wide range of temperature from -60 °C up to 300 °C
- Chiller - integrated within the system's footprint
- Field upgradable for reduced cost of ownership

Software Suite SENTIO®
- Simple and intuitive operation by revolutionary, multi-touch software control saves significant training time
- Scroll, Zoom, Move commands mimic modern smart mobile devices and allows to become an expert in just minutes
- Switching between the active application and the rest of the APPs is just matter of a simple finger sweep
- MPI RF calibration software program QAlibria® is fully integrated with SENTIO® – for ease of use by following a single operational concept methodology

Thermal Control
- Thermal chuck can be operated by using the fully integrated touch-screen display
- Placed at convenient location in front of the operator for fast operation and immediate feedback

Integrated Hardware Control Panel
- Provide faster, safer and convenient system control and test operation
- The keyboard and mouse are strategically located to control the software if necessary and will also control the Windows® based instrumentation

mDrive™ Option
- Provides a truly intuitive, manual operation of all existing programmable stages, such as chuck, scope or MicroPositioners
- X- and Y-axis fine control for the selected stage
- Z safety function requires additional enabling

Vertical Controlled Environment™ (VCE) Option
- Side view of the probe tips – The VCE™ allows contact position automation independent of the probe card tip-drop
- It enables safe working with probe cards or single RF and DC probes

Silicon Photonics Upgrade Option
- Integrates the fiber alignment equipment into the footprint of the probe station
- Optimized probe platen design for maximum stability
- Comfortable operation by full integration into SENTIO® software